



PATENT APPLICATION
Attorney Docket No.: SON-2769

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of

Hidetoshi OHNUMA, et al

Group: 1756

Serial No. 10/603,689

Examiner: Not Assigned

Filed: June 26, 2003

Confirmation No. 2872

For: EXPOSURE METHOD, MASK FABRICATION
METHOD, FABRICATION METHOD
OF SEMICONDUCTOR DEVICE, AND
EXPOSURE APPARATUS

PRELIMINARY AMENDMENT

MS Non-Fee Amendment
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to the initial examination, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the claims begin on page 3 of this paper.

Amendments to the Abstract begin on page 9 of this paper.

Remarks/Arguments begin on page 10 of this paper.